

Application Information

Application number:: 10/123,751

Filing Date:: 04/16/2002

Application Type:: Regular

Subject Matter:: Utility

Suggested classification::

Suggested Group Art Unit::

CD-ROM or CD-R?:: None

Computer Readable Form (CRF)?:: No

Title:: METHOD OF ULTRA-LOW ENERGY ION

IMPLANTATION TO FORM ALLOY LAYERS

IN COPPER

Attorney Docket Number:: 039153-0529 (G1234)

Request for Early Publication?:: No

Request for Non-Publication?:: No

Suggested Drawing Figure::

Total Drawing Sheets:: 3

Small Entity?:: No

Petition included?:: No

Secrecy Order in Parent Appl.?:: No

Applicant Information

Applicant Authority Type:: Inventor

Primary Citizenship Country:: United Kingdom

Status:: Full Capacity

Given Name::	Ercan				
Family Name::	Adem	Adem			
City of Residence::	Sunnyvale				
State or Province of	CA				
Residence::					
Country of Residence::	US				
Street of mailing address::	729 Liverpool Way				
City of mailing address::	Sunnyvale				
State or Province of mailing	CA				
address::					
Postal or Zip Code of mailing	94087				
address::					
Correspondence Information					
Correspondence Customer Nui	mber::	26371			
E-Mail address::		PTOMailMadison@fo	oley.com		
Representative Information					
Representative Customer	i				
Number::					

Domestic Priority Information

Application::	Continuity Type::	Parent	Parent Filing
		Application::	Date::
This Application	Continuation of	10/123,751	04/16/2002

Foreign Priority Information

Country::	Application	Filing Date::	Priority Claimed::
	number::		

Assignee Information

Assignee Name::

Advanced Micro Devices, Inc.